

Amendments to the Claims:

The following listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Currently Amended) A method for manufacturing ceramics on a substrate, comprising:

forming a film-forming region having affinity to ceramics to be formed, and a non-film-forming region having no affinity to the ceramics to be formed, thereby self-alignably forming a ceramic film on the film-forming region, wherein the film-forming region is the partial portion of the substrate

mixing a fine particle of a raw material species which becomes at least part of raw materials for ceramics with an active species having high kinetic energy;

feeding the mixed fine particle and active species to the substrate so that the fine particles of the raw material species are deposited on the substrate while being provided with kinetic energy from the active species; and

increasing the migration energy of atoms in the ceramic film for crystallization of the ceramic film by providing energy to the fine particles of the raw material species by the active species, wherein the ceramic film is formed on a partial portion of the substrate by an LSMCD process or a misted CVD process.

2. (Original) The method for manufacturing ceramics according to claim 1, wherein a diameter of the fine particle is 0.1 μm or less.

3. (Original) The method for manufacturing ceramics according to claim 1, wherein a diameter of the fine particle is 0.01 μm or less.

4. (Original) The method for manufacturing ceramics according to claim 1, wherein the fine particle is electrically charged.

5. (Original) The method for manufacturing ceramics according to claim 1, wherein the fine particle of the raw material species is gasified before being mixed with the active species.

6. (Original) The method for manufacturing ceramics according to claim 1, wherein the active species is a radical or an ion.

7. (Original) The method for manufacturing ceramics according to claim 6, wherein the active species is a radical or an ion of the raw material species which becomes part of the raw materials for ceramics.

8. (Original) The method for manufacturing ceramics according to claim 6, wherein the active species is a radical or an ion of oxygen or nitrogen.

9. (Original) The method for manufacturing ceramics according to claim 6, wherein the active species is an ion obtained by activating inert gas.

10. (Original) The method for manufacturing ceramics according to claim 9, wherein the inert gas is an ion of argon or xenon.

11. (Original) The method for manufacturing ceramics according to claim 1, wherein at least the active species is fed to the substrate in an accelerated state.

12-14. (Canceled)

15. (Original) The method for manufacturing ceramics according to claim 1, wherein the ceramic film is a dielectric.

16. (Original) The method for manufacturing ceramics according to claim 15, wherein the dielectric is formed at a temperature of 600°C or less.

17. (Original) The method for manufacturing ceramics according to claim 15, wherein the dielectric is formed at a temperature of 450°C or less.

18-33. (Canceled)

34. (New) A method for manufacturing ceramics on a substrate, comprising:

forming a film-forming region having affinity to ceramics to be formed on the substrate, and a non-film-forming region having no affinity to the ceramics to be formed on the substrate, thereby self-alignably forming a ceramic film on the film-forming region;

mixing a fine particle of a raw material species which becomes at least part of raw materials for ceramics with an active species having high kinetic energy to form a complex;

feeding the mixed fine particle and active species to the substrate held by a substrate holder so that the fine particles of the raw material species are deposited on the substrate while being provided with kinetic energy from the active species;

biasing the substrate holder to accelerate the complex of the active species and the fine particle of the raw material species during deposition; and

increasing the migration energy of atoms in the ceramic film for crystallization of the ceramic film by providing energy to the fine particles of the raw material species by the active species, wherein the ceramic film is formed by an LSMCD process or a misted CVD process.

35. (New) A method for manufacturing ceramics on a substrate, comprising:

mixing a fine particle of a raw material species which becomes at least part of raw materials for ceramics with an active species having high kinetic energy in a mixing chamber;

after mixing the fine particle and active species in the mixing chamber, feeding the mixed fine particle and active species from the mixing chamber to the substrate so that the fine particles of the raw material species are deposited on the substrate while being provided with kinetic energy from the active species; and

increasing the migration energy of atoms in the ceramic film for crystallization of the ceramic film by providing energy to the fine particles of the raw material species by the active species, wherein the ceramic film is formed by an LSMCD process or a misted CVD process.